

**INFORMATION DISCLOSURE**  
**CITATION IN AN**  
**APPLICATION**  
**(PTO-1449)**

ATTY. DOCKET NO.  
005916 USA/  
FPS/MMCS/MC

**SERIAL NO.**  
**09/998,384**

**APPLICANT**  
**Young Joseph PAIK**

**FILING DATE**  
November 30, 2001

GROUP  
~~2812~~ 2823

## U.S. PATENT DOCUMENTS

[illegible]

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

K.N.	Boning, Duane et al. "Run by Run Control of Chemical-Mechanical Polishing." <i>IEEE Trans.</i> October 1996. Vol. 19, No. 4. pp. 307-314.
K.N.	Moyne, James et al. "A Run-to-Run Control Framework for VLSI Manufacturing." <i>Microelectronic Processing '93 Conference Proceedings.</i> September 1993.
K.N.	Telfeyan, Roland et al. "Demonstration of a Process-Independent Run-to-Run Controller." <i>187<sup>th</sup> Meeting of the Electrochemical Society.</i> May 1995.
K.N.	Moyne, James et al. "A Process-Independent Run-to-Run Controller and Its Application to Chemical-Mechanical Planarization." <i>SEMI/IEEE Adv. Semiconductor Manufacturing Conference.</i> August 15, 1995.
K.N.	Moyne, James et al. "Adaptive Extensions to be a Multi-Branch Run-to-Run Controller for Plasma Etching." <i>Journal of Vacuum Science and Technology.</i> 1995.
K.N.	Sachs, Emanuel et al. "Process Control System for VLSI Fabrication."
K.N.	Chaudhry, Nauman et al. "Active Controller: Utilizing Active Databases for Implementing Multi-Step Control of Semiconductor Manufacturing." <i>University of Michigan.</i> pp. 1 – 24.
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K.N.	Chaudhry, Nauman A. et al. "A Design Methodology for Databases with Uncertain Data." <i>University of Michigan.</i> pp. 1 – 14.
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K.N.	Moyne, James et al. "Yield Improvement @ Contact Through Run-to-Run Control."
K.N.	Kim, Jiyoung et al. "Gradient and Radial Uniformity Control of a CMP Process Utilizing a Pre- and Post-Measurement Strategy." <i>University of Michigan.</i>

**EXAMINER**

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

11 / 02 / 05



PTO/SB/08a/b (07-05)

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Substitute for form 1449A/B/PTO				<b>Complete if Known</b>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				Application Number	09/998,384
				Filing Date	November 30, 2001
				First Named Inventor	Young J. PAIK
				Art Unit	2823
				Examiner Name	K. D. Nguyen
Sheet	1	of	1	Attorney Docket Number	005916 USA/FET/FET/DV

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
K.N.	AA*	US-6,093,080	07-25-2000	Inaba et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)				

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NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
K.N.	CA	Office Action dated 07/01/2005 from U.S. Patent Application No. 11/118,711, filed 04/29/2005.	

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<sup>1</sup> Applicant's unique citation designation number (optional). <sup>2</sup> Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	<i>K. D. Nguyen</i>	Date Considered	01/20/06
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